1. **Equipment:** E-beam Evaporation System
2. **Indentor:** Dr. Siva Rama Krishna Vanjari
3. **Location:** Nano-X workshop
4. **Preference of slot types:** Continuous three hour slots
5. Hours: 3
6. Samples: 2-3 samples can be loaded simultaneously
7. **Tentative cost per slot/sample:** INR 500 per slot (3 hrs)
8. Contact Details: Dr. Siva Vanjari
9. Rules and guidelines:
10. Samples/materials allowed in the equipment: Silicon/ Silicon based materials, glass substrates. Non-volatile, non-contaminating organic samples on silicon/glass or flexible substrates
11. Restricted materials/samples in the equipment: Volatile substances, Non-CMOS, Non-MEMS process materials
12. Evaporator material is a consumable. The user has to provide the same or separate cost needs to be paid for the material if it is available with the operator.
13. The user will have to prepare the sample, but she/he may consult the operator for choosing an appropriate technique. The maximum substrate height is 4 mm. Unclean/Contaminated substrates are not allowed. Contact operator one day in advance about the cleaning procedure.
14. To reduce chances, the substrates should be preserved in a vacuum a desiccator after cleaning till it is inserted in the Evaporation for observation. This will improve adhesion between the substrate and the thin film
15. For clarifications, you may contact Dr. Siva Vanjari You can reach him by email (svanjari@iith.ac.in) or telephone (040-2301-7086).